

## Application Data Sheet

### **Application Information**

Application Type:: Regular  
Subject Matter:: Utility  
Suggested Group Art Unit:: N/A  
CD-ROM or CD-R?:: None  
Sequence submission?:: None  
Computer Readable Form (CRF)?:: No  
Title:: METHOD OF FORMING SI-CONTAINING THIN FILM  
Attorney Docket Number:: 09852/0200879-US0  
Request for Early Publication?:: No  
Request for Non-Publication?:: No  
Suggested Drawing Figure:: 1  
Total Drawing Sheets:: 2  
Small Entity?:: No  
Petition included?:: No  
Secrecy Order in Parent Appl.?:: No

### **Applicant Information**

Applicant Authority Type:: Inventor  
Primary Citizenship Country:: Japan  
Status:: Full Capacity  
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### **Correspondence Information**

Correspondence Customer Number:: 07278

### **Representative Information**

Representative Customer Number:: 07278

### **Foreign Priority Information**

Country::	Application number::	FilingDate::	Priority Claimed::
Japan	2003-034560	02/13/03	Yes
Japan	2004-005285	01/13/04	Yes

### **Assignee Information**

Assignee name:: MITSUBISHI MATERIALS CORPORATION  
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